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(54) **Title:** DEGAS MODULE FOR PULSED LASER DEPOSITION

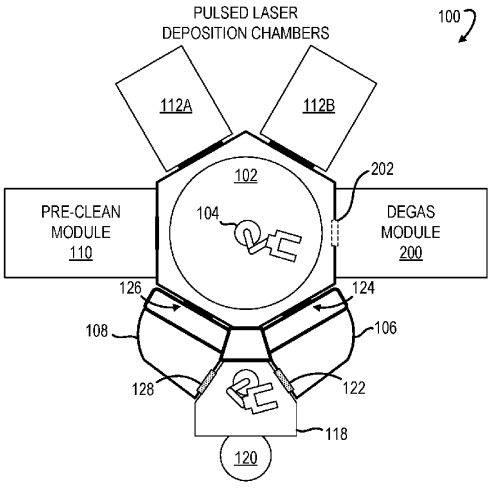


FIG. 1

(57) **Abstract:** Examples are disclosed that relate to treating a substrate in a degas module to remove water vapor prior to depositing a film by pulsed laser deposition. One example provides a processing tool. The processing tool comprises a transfer module. The processing tool further comprises a pulsed laser deposition module connected to the transfer module. The processing tool further comprises a degas module connected to the transfer module. The degas module comprises a substrate support. The degas module further comprises a cryopump configured to form a high vacuum ($P \leq 10^{-5}$ Torr) in the degas module and the transfer module. The degas module further comprises an infrared radiation source.

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